



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 10/783,242
Filing Date February 19, 2004
Confirmation No. 1437
Inventor Garo J. Derderian et al.
Assignee Micron Technology, Inc.
Group Art Unit 2812
Examiner Alexander G. Ghyka
Attorney's Docket No. MI22-2403
Customer No. 021567
Title: Atomic Layer Deposition Method of Forming an Oxide Comprising
Layer on a Substrate

RESPONSE TO JUNE 8, 2005 OFFICE ACTION

To: Mail Stop Amendment
Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

VIA U.S. EXPRESS MAIL

From: Mark Matkin (Tel. 509-624-4276; Fax 509-838-3424)
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Responsive to the Office Action dated June 8, 2005, Applicant amends
and remarks as follows:

AMENDMENTS